

Title (en)

MICROSCOPE SYSTEM FOR TESTING SEMICONDUCTORS

Title (de)

MIKROSKOPSYSTEM ZUM PRÜFEN VON HALBLEITERN

Title (fr)

SYSTEME DE MICROSCOPE UTILISE POUR VERIFIER LES SEMI-CONDUCTEURS

Publication

EP 1849038 A2 20071031 (EN)

Application

EP 06719077 A 20060119

Priority

- US 2006002109 W 20060119
- US 64874705 P 20050131
- US 64895105 P 20050131
- US 64895205 P 20050131

Abstract (en)

[origin: WO2006083581A2] A system that includes an imaging device for effectively positioning a probe for testing a semiconductor wafer.

IPC 8 full level

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CPC (source: EP)

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Citation (search report)

See references of WO 2006083581A2

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DOCDB simple family (publication)

WO 2006083581 A2 20060810; WO 2006083581 A3 20070705; DE 202006020618 U1 20090312; EP 1849038 A2 20071031; JP 2008529304 A 20080731; TW 200703535 A 20070116; TW I304625 B 20081221

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